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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10057804	FILING DATE 01/25/2002	CLASS 438	SUBCLASS -	GAU 2812	EXAMINER Thomas, Eric
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**APPLICANTS: Tsuruta Hideyoshi; Yamada Satoru; Washimoto Kiyoshi; Miyazaki Naoki;

**CONTINUING DATA VERIFIED:

** FOREIGN APPLICATIONS VERIFIED:
JAPAN 2001-19,487 01/29/2001

PG-PUB DO NOT PUBLISH ☐

RESCIND ☐

Foreign priority claimed ☐ yes ☐ no
35 USC 119 conditions met ☐ yes ☐ no
Verified and Acknowledged Examiners's initials

ATTORNEY DOCKET NO

782 215

TITLE : Electrostatic chuck and substrate processing apparatus

U.S. DEPT. OF COMM./PAT. & TM-PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		Primary Examiner	DRAWING	
Amount Due	Date Paid		Sheets Drawg.	Figs. Drawg.
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	Application Examiner	
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